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Laser conditioning of UV anti-reflective optical coatings for applications in aerospace

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ABSTRACT

In this work we study the effect of laser conditioning on laser-induced damage of ion-beam sputtered, anti-reflection coated laser optics with ns-pulsed laser radiation at a wavelength of 355 nm. With respect to applications in aerospace, measurements were performed under high vacuum. At laser fluences below 20 J/cm², laser-induced damage appears as pin-point damage (small explosion pits with sizes in the range of 1 μm), sometimes referred to as “grey haze”. We find that ramped laser conditioning is an effective tool to reduce not only the abundance but also the average size of pin-point damage at laser fluences exceeding the optic’s unconditioned laser-induced damage threshold. We discuss our results in the context of the small absorber model for damage crater formation.

Keywords: Laser-induced damage, ion-beam sputtering, anti-reflection coating, aerospace, radiation, crater formation

1. INTRODUCTION

The understanding, mitigation and risk-assessment of laser-induced damage in optical coatings for high-power laser systems is a key topic for many scientific (e.g. nuclear fusion¹, particle physics²) and industrial (e.g. lithography³, material processing) applications, as well as for laser development in general. A particular focus of the Laser Optics Test Center of the DLR is the advancement and qualification of optics for laser systems used in air- and spacecraft missions. For example, we have recently selected and qualified all relevant laser optics for the Atmospheric Laser Doppler LIDAR Instrument (ALADIN)^{4,5}, which was launched to space aboard the Aeolus wind satellite on August 22nd 2018, as part of ESA’s Earth Explorer Missions.

Some of the most mission-challenging parts in space borne laser systems for the ALADIN as well as future space lasers are optical components with anti-reflection coatings for ultra-violet (UV) laser radiation. For this purpose, almost all space optics are coated via Ion Beam Sputtering (IBS), as the high kinetic energy deposition of this coating technology produces dense coatings, which have been shown to withstand the harsh environmental conditions (e.g. ultra-high vacuum⁶, energetic radiation⁷, atomic oxygen and hydrocarbon contaminants) encountered in space applications.

Laser-induced damage in transparent optical materials is driven by absorption from nanometer sized defects or impurities almost inevitably produced during the manufacturing process of the optical substrates and coatings.^{8–10} From our experience in damage testing of optics from different suppliers, many optical coatings and even pure substrates show small damages with damage sizes in the range of 1 μm, when irradiated with laser fluences of a few J/cm². This type of damage morphology is sometimes referred to as “grey haze”¹¹, “micro-pits”¹² or “pin-point damage”¹³ in the literature. The most likely origin of these damages is that they emerge from residual particles (e.g. from CeO₂, a typical polishing material¹⁴) or subsurface damage (SSD).^{15–17} In fact, SSD and particle contamination might be closely related, because impurities can be trapped in the subsurface voids.¹⁸

While the ultimate goal in the manufacturing of optical coatings is to entirely avoid such residual particles, cleaning is always just a form of dilution and some particles and defects will remain in any optical coating. Thus, we underwent some effort in order to study the formation of micro-pits in Al₂O₃/SiO₂ IBS anti-reflection coatings at 355 nm in more detail. In particular, we measured the density and size distributions of micro-pits formed upon laser irradiation as a function of the laser fluence and number of applied laser pulses. Furthermore, we present results of experiments in which we tested different versions of laser conditioning in order to mitigate micro-pit formation.^{19–22}

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2. EXPERIMENTAL

Figure 1 shows a schematic of our optical test bench used for laser induced damage testing. In short, an injection-seeded, Q-switched, diode pumped Nd:YAG laser (Innolas DPSS 500) generates nanosecond, pulsed (repetition rate of 100 Hz) infrared laser radiation at 1064 nm. The third harmonic at 355 nm ($\tau_{FWHM} = 8.5$ ns) is generated in 2 LBO crystals and the energy can be controlled via an energy attenuator which consists of a motorized, $\lambda/2$ -waveplate and a polarizing beam splitter. A beam splitter redirects a fraction of the laser beam to a calibrated detector for an online measurement of the pulse energy. We use computer-controlled electronic shutters in order to expose the laser optics to a defined number of laser pulses. The laser beam is focused into the high-vacuum chamber (pressure $< 1 \times 10^{-6}$ mbar) with an $f = 750$ mm lens and irradiates the optical component under investigation. The vacuum chamber is mounted on an electronic xy-translation stage to allow for the irradiation of different positions on the sample. The beam profile is measured in a plane equivalent to the optical component's surface with a CCD camera.

For this particular study, we investigate commercial laser windows from the same batch with an anti-reflection coating (AR@355nm/0°, Al₂O₃/SiO₂) on the front side (uncoated back side), which was generated via ion beam sputtering (IBS). During typical laser-induced damage tests, we use an online damage detection system which consists of a chopped HeNe laser beam at 632 nm that is spatially overlapped with the damaging UV laser. In the case of a damage on the optical surface, the scatter of the red laser light increases and is detected as a lock-in amplified signal of a silicon photodiode behind the vacuum chamber. Unfortunately, for very small damages (< 5 μ m) the online detection is not very sensitive. Therefore, we characterize the optical damage by differential interference contrast (DIC or Nomarski) microscopy (Olympus BX61 with 50 \times magnifying lens) ex-situ after damage testing.

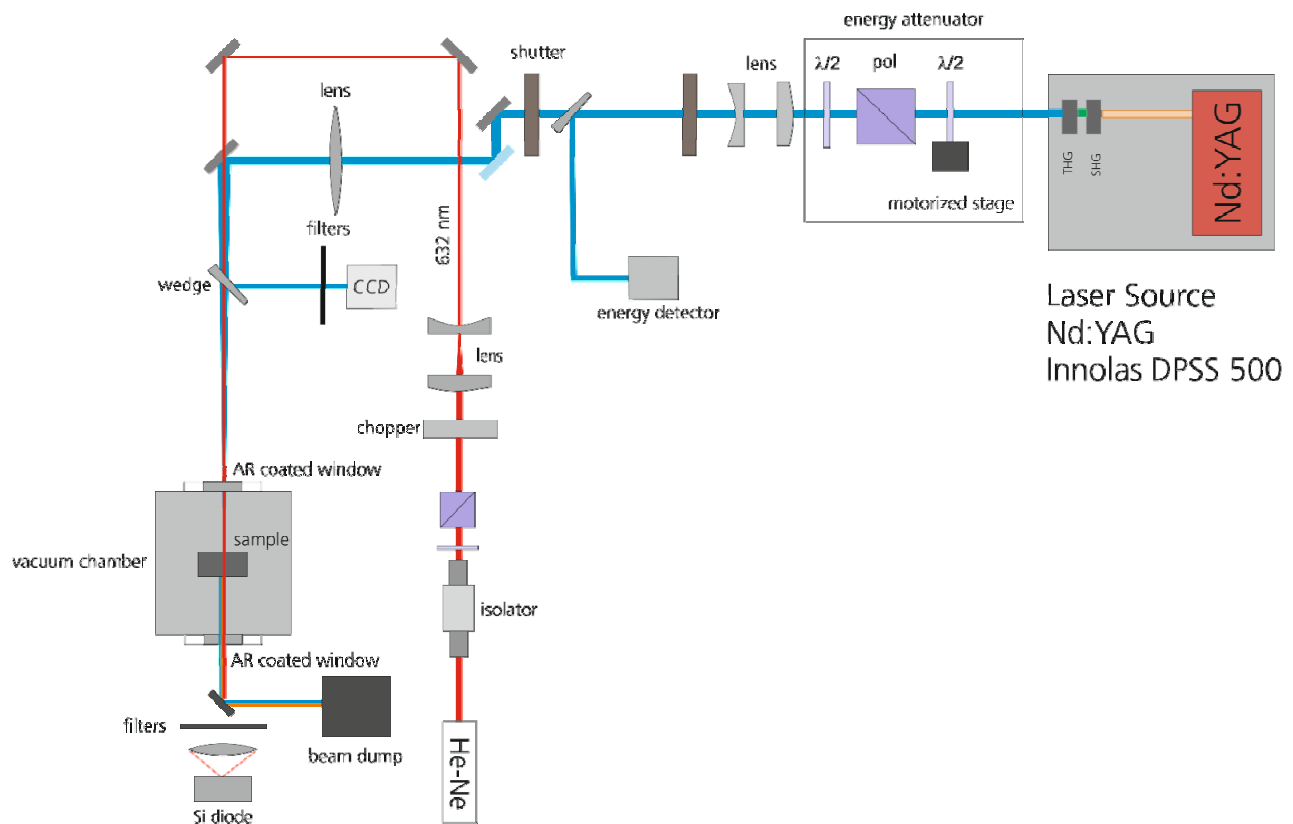


Figure 1: Experimental setup for laser-induced damage testing.

3. FORMATION AND SIZE DISTRIBUTIONS OF PIN-POINT DAMAGES

In a first experiment, different positions (distance between positions of 1.5 mm) on the optical sample were irradiated with predefined numbers of laser pulses (between 1 and 50,000 shots at 100 Hz) at predefined laser fluences (between 12 and 30 J/cm²).

Figure 2 shows examples of Nomarski micrographs for different irradiation sites. The top panels (A-C) show the typical laser damage at a high laser fluence of 30 J/cm², which is significantly higher than the LIDT of ~7 J/cm² (0% damage probability at 10k pulses) for the investigated sample. After 1 laser pulse at 30 J/cm² (panel A) the Nomarski micrograph shows pin-point damages. After 5 laser pulses (panel B), there is an onset of delamination and after 1,000 laser pulses (panel C) we observe massive bulk damage. This is an example for a complete breakdown of the functionality of the laser optics, which would certainly lead to a mission failure of a space mission targeting laser based measurements.

As opposed to this, at a laser fluence of 15 J/cm² (panels D-F of Figure 2), there is also a formation of pin-point damages. However, as we will show in more detail within this work, these damages are generated within the first laser pulse and do not grow upon subsequent irradiation. In fact, it is not possible to distinguish Nomarski images taken of a spot irradiated with 1 (panel D) from a spot irradiated with 50,000 laser pulses (panel F).

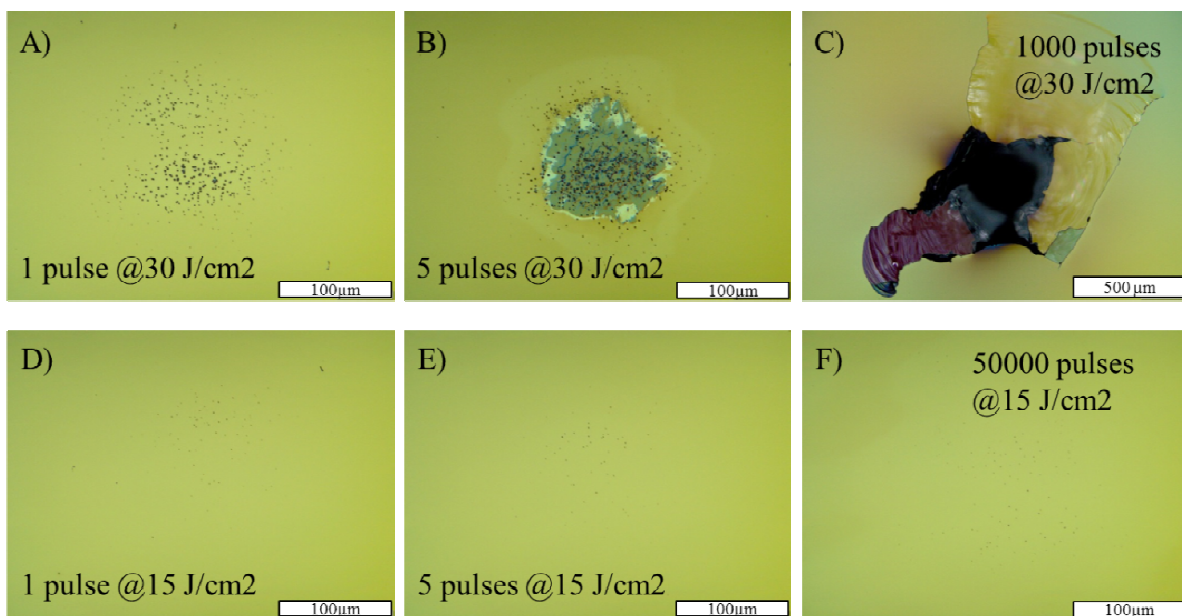


Figure 2: Nomarski micrographs showing the damage morphology after irradiation of different positions on the same IBS-coated optic for different laser fluences and pulse numbers as indicated in the figure. The scale of the micrographs is 100 μm, except for the one showing bulk damage (panel C) which has a scale of 500 μm.

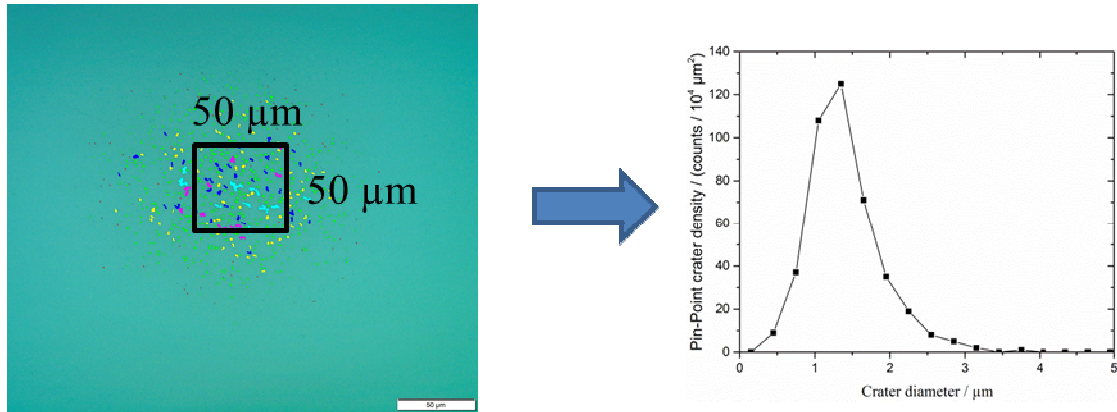


Figure 3: Concept for the extraction of size distributions from differential interference contrast (Nomarski) micrographs.

Damages are detected by pattern recognition of the micrograph. Pin-point damages in the figure are colored according to their size. All detected damages within a central area of $50 \times 50 \mu\text{m}^2$ are then binned in intervals of $0.3 \mu\text{m}$ according to their mean crater diameter to obtain a pin-point crater density distribution as shown in the panel on the right.

In order to quantify laser-induced damage, we analyze the density of micro-pits (number of micro-pits per area) within a central area of $50 \times 50 \mu\text{m}^2$ in which the laser fluence is above 90 % of the peak laser fluence for the laser beam diameter of $1/e^2 = 240 \mu\text{m}$, see Fig. 3. The analysis is performed with a native software tool of the DIC microscope, which searches for connected dark pixels representing pin-point damages. The software is set to detect damages with sizes above $0.3 \mu\text{m}$.

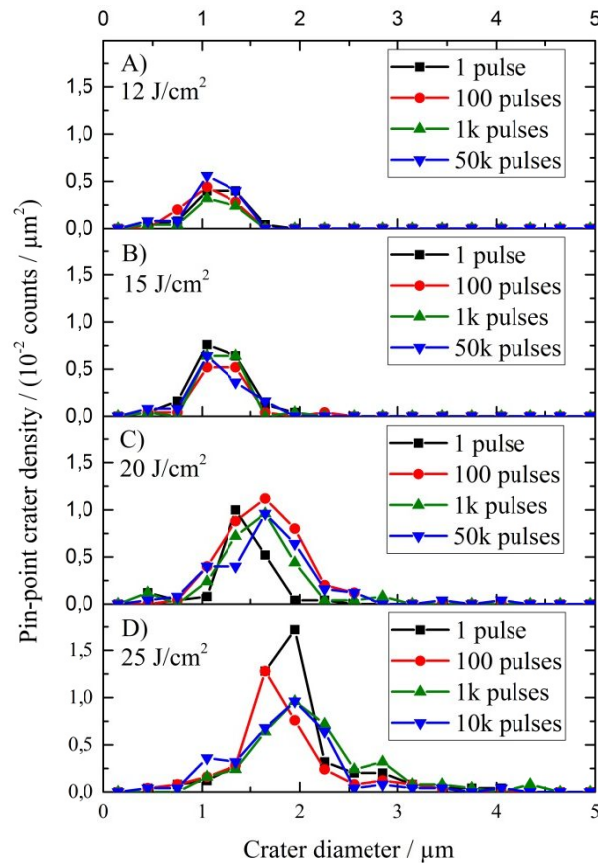


Figure 4: Crater density of pin-point damages as function of the crater diameter for different on axis peak laser fluences between 12 and 25 J/cm^2 and for different numbers of subsequently applied laser pulses as indicated in the plot legends.

Figure 4 shows a compilation of results for the crater density as function of the crater diameter for different on axis peak laser fluences between 12 and 25 J/cm² and for different numbers of subsequently applied laser pulses. Each data point represents a different position on the optical surface. In Figure 5, we furthermore extract the total number densities (top panel) and the mean diameter (middle panel) of pin-point damages, as well as the fraction of damaged surface area (bottom panel) within the analyzed 50×50 μm² frame.

We find that both the density and the mean diameter of pin-point damages strongly increase with increasing laser fluence. More specifically, the density rises from ~1×10⁻²/μm² to ~5×10⁻²/μm² and the mean diameter increases from ~1.1 μm to ~2.2 μm when comparing the data at 12 J/cm² with the data at 30 J/cm². As a result, also the fraction of damaged area increases with higher laser fluence.

In the fluence range between 12 and 20 J/cm², these damage parameters are essentially independent of the applied number of laser pulses. This supports the conclusion that micro-pits are predominantly formed during the first laser pulse. With subsequent laser irradiation at the same laser fluence, these damages do not grow and there are no new damages. This is because all susceptible absorbing impurities/defects in the irradiated region have already been converted into pin-point damages during the first laser pulse. At higher laser fluences such as 25 or 30 J/cm² we observe delamination which then leads to bulk damage (compare panels B) and D) of Figure 2) at higher pulse numbers. Therefore, the micro-pit densities, diameters and the fraction of damaged area could not be evaluated and Figure 5 does not contain data points for these cases.

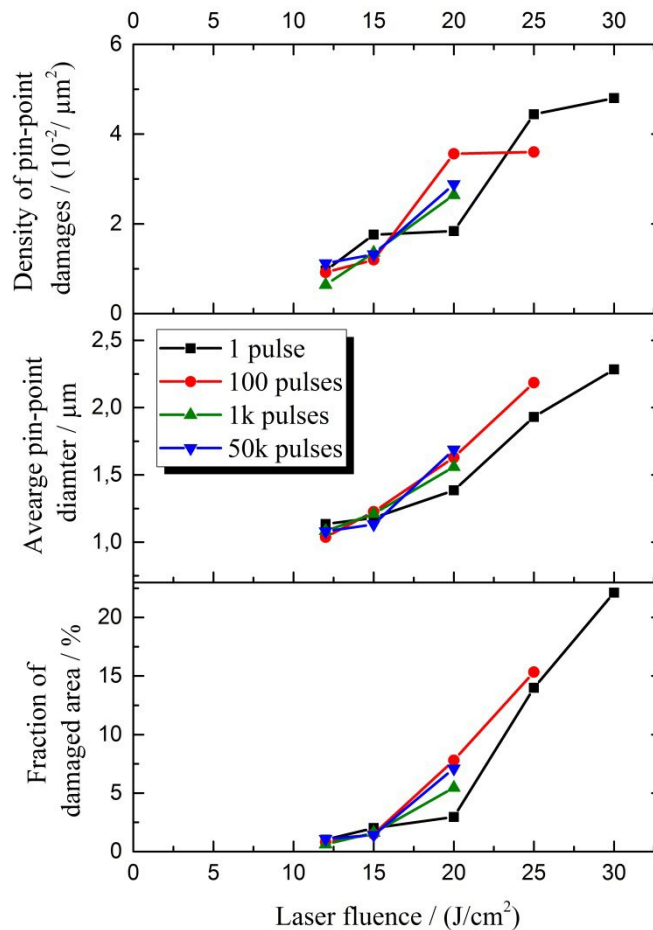


Figure 5: Density of pint-point damages (top panel), their average diameter (middle panel) and fraction of damaged area (bottom panel) in the analyzed region of 50×50 μm² as function of the laser fluence. The different traces in each panel correspond to different pulse numbers as given in the figure legend.

4. EFFECT OF LASER CONDITIONING ON SIZE DISTRIBUTIONS OF PIN-POINT DAMAGES

We decided to test two different protocols for laser conditioning and evaluated their influence on laser-induced pin-point damages.

In a first approach, each test position on the optical components' surface was irradiated with 1.000 laser pulses at a laser fluence of 6 J/cm^2 (which is below the LIDT of 7 J/cm^2) and then with 1000 laser pulses at a different laser fluence at the same position. We refer to this test protocol as "classical" (below threshold) laser conditioning. In a second approach, the laser fluence at each test position was ramped from 6 J/cm^2 to the final fluence (between 10 and 25 J/cm^2) in steps of 1 J/cm^2 with 1.000 laser pulses for each step. We refer to this test protocol as "ramped" laser conditioning.

Figure 6 compares distributions of the pin-point damage crater density for the unconditioned (top panel) laser optic with results for the "classical" (middle panel) and "ramped" (bottom panel) laser conditioned sample. Similar to the previous section of this publication, we further analyze the data by extracting the density of damages as well as their mean diameter and the fraction of damaged area, see Figure 7. We would like to mention, that compared to the data presented in Section 3, we used a larger UV laser beam diameter ($1/e^2=340 \mu\text{m}$) and thus also investigated a larger area ($100 \times 100 \mu\text{m}^2$) for the analysis of damages.

From the data we find that while both laser conditioning protocols succeed in reducing the density and average size of pin-point damages, the results of the ramped laser conditioning protocol are much better. In particular, for a laser fluence of 15 J/cm^2 , there is essentially no laser-induced damage for the ramped laser conditioning. This means that laser conditioning allows the investigated optics to be used at a laser fluence exceeding the LIDT by more than a factor of 2.

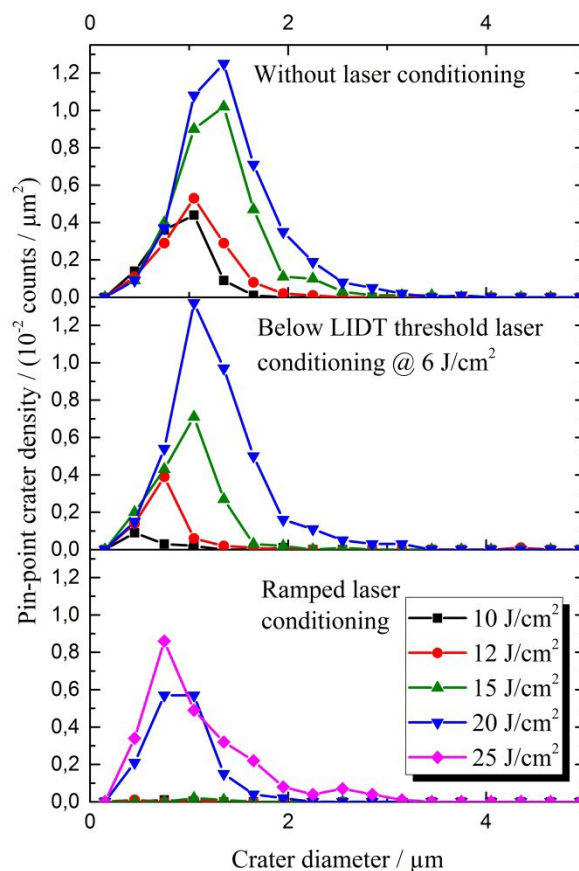


Figure 6: Comparison of size distributions for pin-point damages without (top panel) laser conditioning as well as with classical (below LIDT threshold, middle panel) and ramped (bottom panel) laser conditioning.

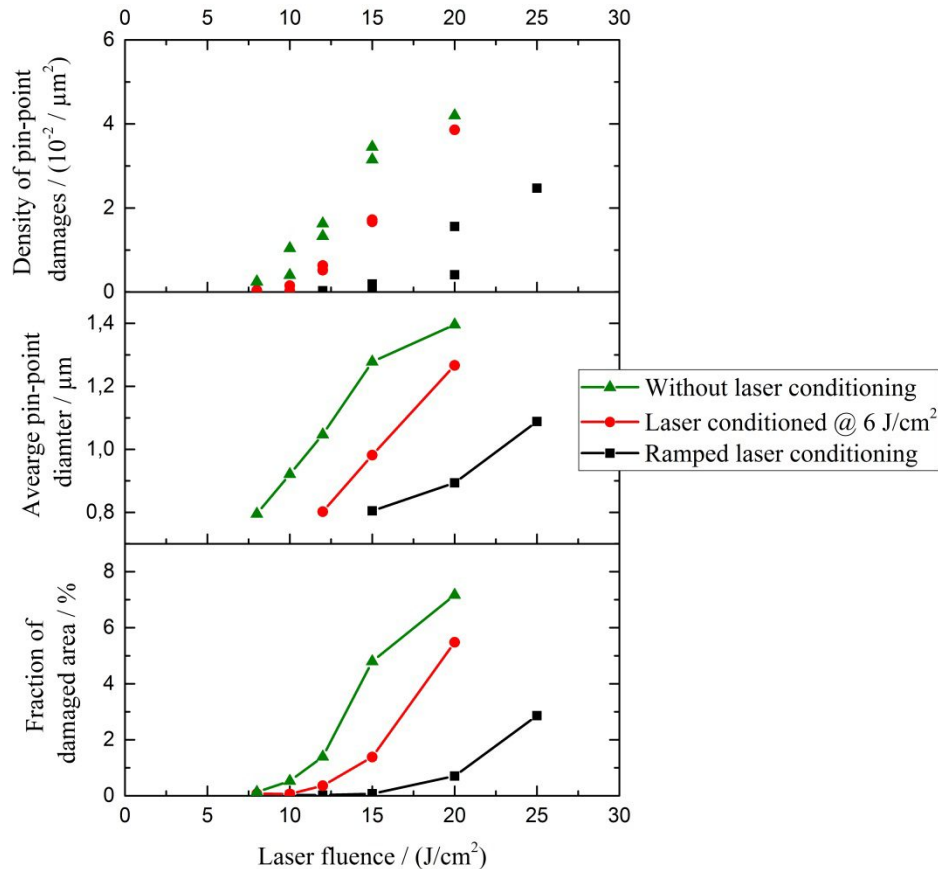


Figure 7: Density (top panel), average diameter (middle panel) and fraction of damaged area (bottom panel) in the analyzed region of $100 \times 100 \mu\text{m}^2$ as function of the laser fluence. We have performed two runs of the experiment and in the top panel there are thus two different data points at each fluence for the evaluated density of pin-point damages. The missing data points at 20 and 25 J/cm^2 represent delamination or bulk damage and thus could not be evaluated. For the calculation of the average diameter and fraction of damaged area we averaged the available data from the two runs.

We would like to note in passing, that we also performed a test to verify the permanence of the laser conditioning effect. For this test, we ramped the laser fluence at a position on the sample to a specific value (e.g. up to $20 \text{ J}/\text{cm}^2$), waited for two days (the sample was still under vacuum) and then directly exposed the sample to the specified laser fluence. We found that the second exposure did not lead to additional micro-pits. Thus, the laser conditioning effect is permanent (at least for a time of 2 days under vacuum).

5. DISCUSSION OF THE RESULTS WITHIN A SMALL ABSORBER MODEL

In this chapter we discuss our results within a model of small, localized absorbers^{8-11,23-25}. Within this model, damage is initiated around nanoscale absorbers. These small absorbers (compared to larger absorbers) have a low heat capacity with respect to their absorbing surface area and thus absorption of laser radiation results in a rapidly increasing local temperature. This temperature may reach several 1.000 Kelvin, thereby generating a plasma in the vicinity of the defect.²⁵ This plasma itself starts absorbing energy and energy is accumulated during the laser pulse until being released in a micro-explosion. As the crack formation/micro-explosion occurs on a characteristic timescale ($>10^{-8}\text{s}$) longer than the laser pulse duration, the plasma around the nanoscale absorber can gather an excess energy above the threshold for crack formation.²⁶ This excess energy drives the micro-explosion and determines the crater size, explaining the trend that the average diameter of pin-point damages increases with higher laser fluence. In the investigated anti-reflective coating with a thickness of only $\sim 120 \text{ nm}$, the damage is initiated close to the surface and material is ejected.¹¹

The interesting question is how the increase of a laser-induced damage resistance in the studied system due to laser conditioning (observed e.g. in KTP crystals²⁷, bare substrates⁸ and other IBS sputtered films²¹) can be explained within this small absorber model. Previously, UV laser conditioning was attributed to a mechanism in which melting of the inclusion as well as the surrounding matrix results in a dispersion of the inclusion in the host material.^{8,20,26} This dispersion then leads to a decreased density of absorbed energy and thus a higher damage threshold.

An alternative explanation to this dispersion based model is that laser radiation above the laser-induced damage threshold actually leads to a small micro-explosion in any case (even in case of laser conditioning). If it is accepted that the crater size is governed by this excess energy, it is clear that in order to generate none (meaning too small to be detected) or at least only small damages, each localized absorber should be “destroyed” with the smallest possible excess energy. This explains why the ramped laser conditioning is far superior to the “classical”, below laser-induced damage threshold laser conditioning. In fact, up to a laser fluence of 15 J/cm², the ramped laser conditioning increases the damage resistance of the material and we detect almost no change in the surface morphology.

The idea of understanding laser conditioning as a form of micro-explosion with small excess energy is not necessarily a contradiction to the dispersion based understanding of laser conditioning. The reality might be that both effects exist in the investigated optical coating and complement each other.

6. CONCLUSIONS AND OUTLOOK

We demonstrated that ramped laser conditioning is an effective tool to reduce not only the abundance, but also the average size of pin-point damages in IBS sputtered anti-reflection coated laser optics at 355 nm. The observed data is consistent with a model in which pin-point damage originates from micro-explosions at small localized absorption centers. Ramped laser conditioning is superior to below threshold laser conditioning because each defect/inclusion is destroyed with smallest possible excess energy.

An idea to further mitigate nano-absorbers in optical coatings is to apply laser conditioning already during the IBS coating process. This would allow for evaporating possible impurities and inclusions before they are even buried in the optical coating. In fact, such experiments are currently in preparation in an ESA project (ESA Contract No. 4000119563/17/NL/BJ) in cooperation with Laser Zentrum Hannover (LZH).

From our experience with laser optics for space applications, the highest risk for the long term durability of optical coatings is their resistance with respect to laser-induced molecular contamination (LIMC). In fact, we have recently shown that the localized heating of nano-inclusions can enhance LIMC via local heating, even though the nanometer-sized inclusions are not in direct contact with the contaminant.^{28,29} Thus, in future work we would like to assess, whether laser conditioning (either after or during the coating process) also benefits the mitigation of laser-induced damage for high-power laser optics in “real world”, space-like environments.

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